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Atty. Dkt. No. 039153-0310 (F0797)

*Yes  
Changed*

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: Calvin T. Gabriel et al.

Title: PROCESS FOR IMPROVING  
THE ETCH STABILITY OF  
ULTRA-THIN PHOTORESIST

Appl. No.: 09/819,552

Filing Date: 3/28/2001

Examiner: Binh X. Tran

Art Unit: 1765

<b>CERTIFICATE OF FACSIMILE TRANSMISSION</b> I hereby certify that this paper is being facsimile transmitted to the United States Patent and Trademark Office, Alexandria, Virginia on the date below.  Kathryn J. Berg (Printed Name)  <i>Kathryn J. Berg</i> (Signature)  July 6, 2004 (Date of Deposit)
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**AMENDMENT AND REPLY UNDER 37 CFR 1.116**

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

This communication is responsive to the Final Office Action dated May 4, 2004,  
concerning the above-referenced patent application.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2  
of this document.

**Remarks/Arguments** begin on page 6 of this document.

Please amend the application as follows:

07/13/2004 RHOLLAND 00000001 061447 09819552

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001.1652243.1

Application No. 09/819,552